

INFORMATION DISCLOSURE CITATION



Docket: 015559-250	Serial. No.: 09/909,847
Applicant: Alain Izadnegahdar et al.	
Filed: 7/20/2001	Group: 2855 3729

U.S. PATENT DOCUMENTS

Examiner	Document No.	Date	Name	Class	Sub	
<i>NDT</i>	6,444,487	9/2002	Boggs et al.	—	—	
<i>NDT</i>	6,001,666	12/1999	Diem et al.	—	—	

FOREIGN PATENT DOCUMENT

							Trans	
Examiner	Document No.	Date	Country	Class	Sub		Y	N

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

<i>NDT</i>	Kaneko, S. et al., "Monolithic Fabrication of Flexible Film and Thinned Integrated Circuits," Proceedings IEEE 10 th Annual Workshop on MEMS, 1997
Examiner: <i>[Signature]</i>	Date Considered: 2/20/04

* Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609.
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U.S. PATENT DOCUMENTS

Examiner	Document No.	Date	Name	Class	Sub	
<i>NOT</i>	6,316,796	11/2001	Petersen et al.	1	1	
<i>NOT</i>	6,084,257	07/2000	Petersen et al.	1	1	
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Examiner	Document No.	Date	Country	Class	Sub		Y	N

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

<i>NOT</i>	Petersen, K. et al., "Surface Micromachined Structures Fabricated with Silicon Fusion Bonding," 1991 IEEE, pp. 397-399 (5/1991)
<i>NOT</i>	Petersen, K. et al., "Silicon Fusion Bonding for Pressure Sensors," 1988 IEEE, pp. 144-147 (4/1988)
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